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[54] COATING APPARATUS

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[57] ABSTRACT

According to the present invention, there is provided an coating apparatus including means for holding an object to be process, the object holding means rotating in a state in which the object is placed thereon, a ring-like cup situated on an outer side of the object holding means, processing solution supply means, provided above the object, for supplying a processing solution on a surface of the object, discharge means, provided underneath the ring-like cup, for discharging processing solution portions scattered around when the processing solution is supplied on the surface of the object as a waste solution, together with a gas, and storage means, connected to the discharge means, for storing the waste solution and the gas discharged from the discharge means, wherein the waste solution and the gas are separated from each other in the storage means.

13 Claims, 11 Drawing Sheets

